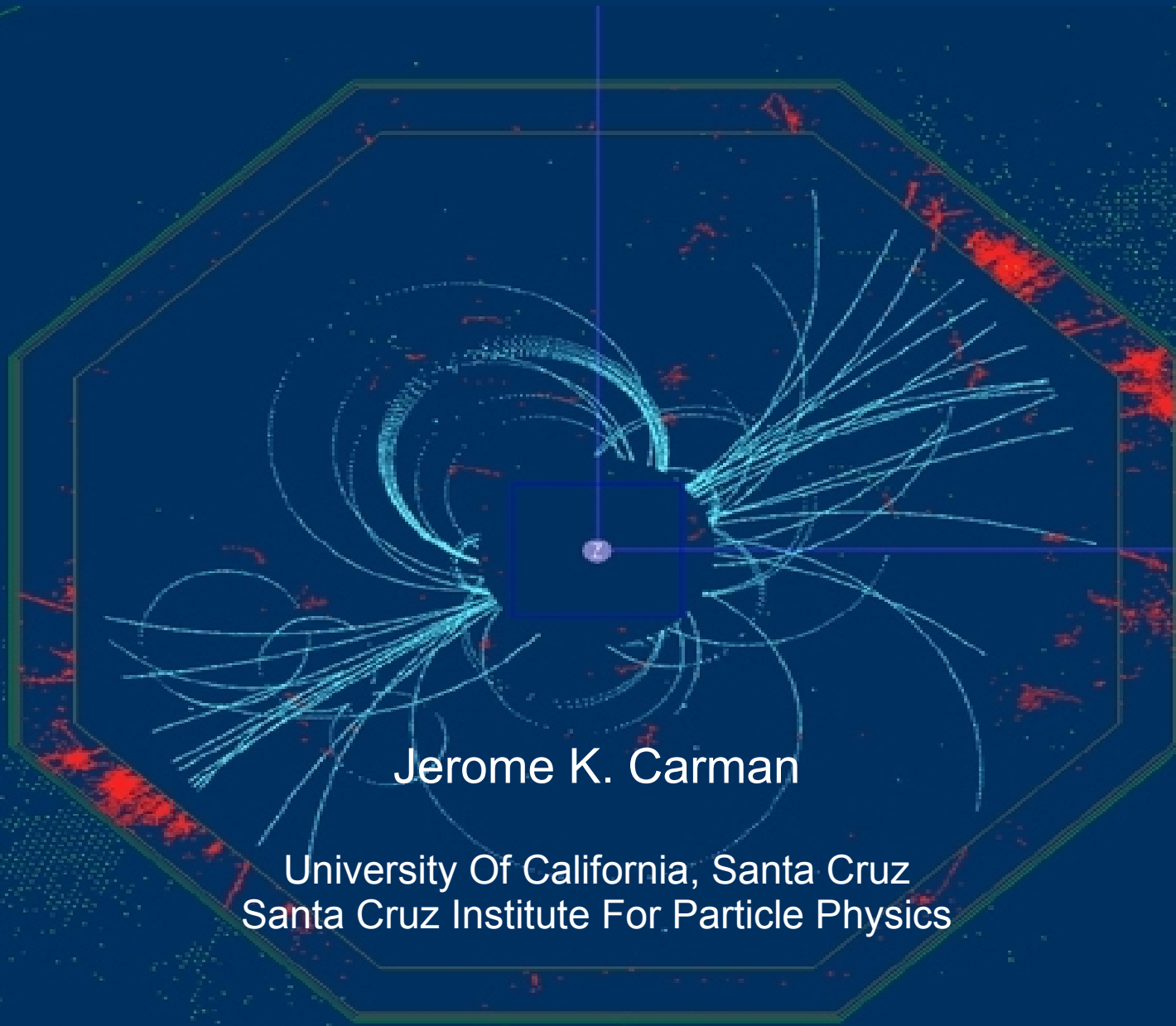




Measurement Of Longitudinal Position For Silicon Strip Detectors Via Charge Division



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What methods exist for longitudinal position measurements?^{1,2}

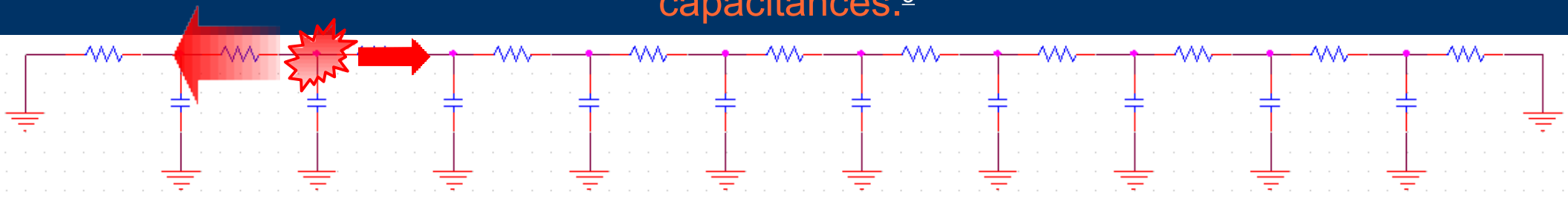
- Diffusive RC Line (noise dominated by the RC line)
 - ◆ Charge Division Method
 - Inherently linear for optimum shaping
 - Resolution is independent of resistance (both total as well as variations along the length of the diffusive line)
 - ◆ Rise Time Method
 - Not inherently linear
 - Sensitive to variations in both resistance and capacitance
- Delay Line (noise dominated by external sources (i.e. amplifiers))
 - ◆ Not efficient use of material
 - ◆ Requires significant line inductance to work

Motivated specifically by a paper written by V. Radeka in 1974 entitled “Signal, Noise And Resolution In Position-Sensitive Detectors”.¹

- Most interesting is the claim that position resolution is independent of resistance for a diffusive line for relevant shaping times.

- $$\frac{\Delta L}{L} \approx \chi \left(\frac{\sqrt{kTC}}{Q_s} \right)$$
 - χ = coefficient which depends on the shaping function
 - kT = from parallel Johnson noise contribution
 - C = total detector capacitance
 - Q_s = total signal charge

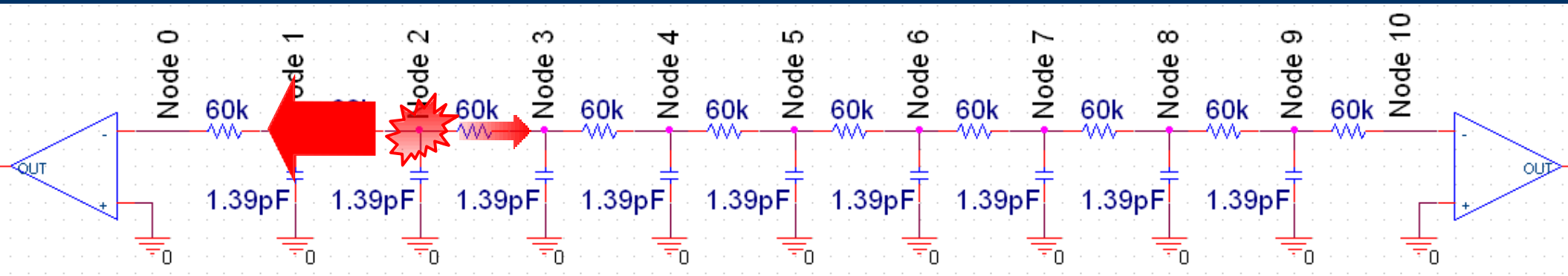
The diffusive line property of a silicon strip detector is modeled as a simple one dimensional RC line with a homogeneous distribution of discrete resistances and capacitances.³

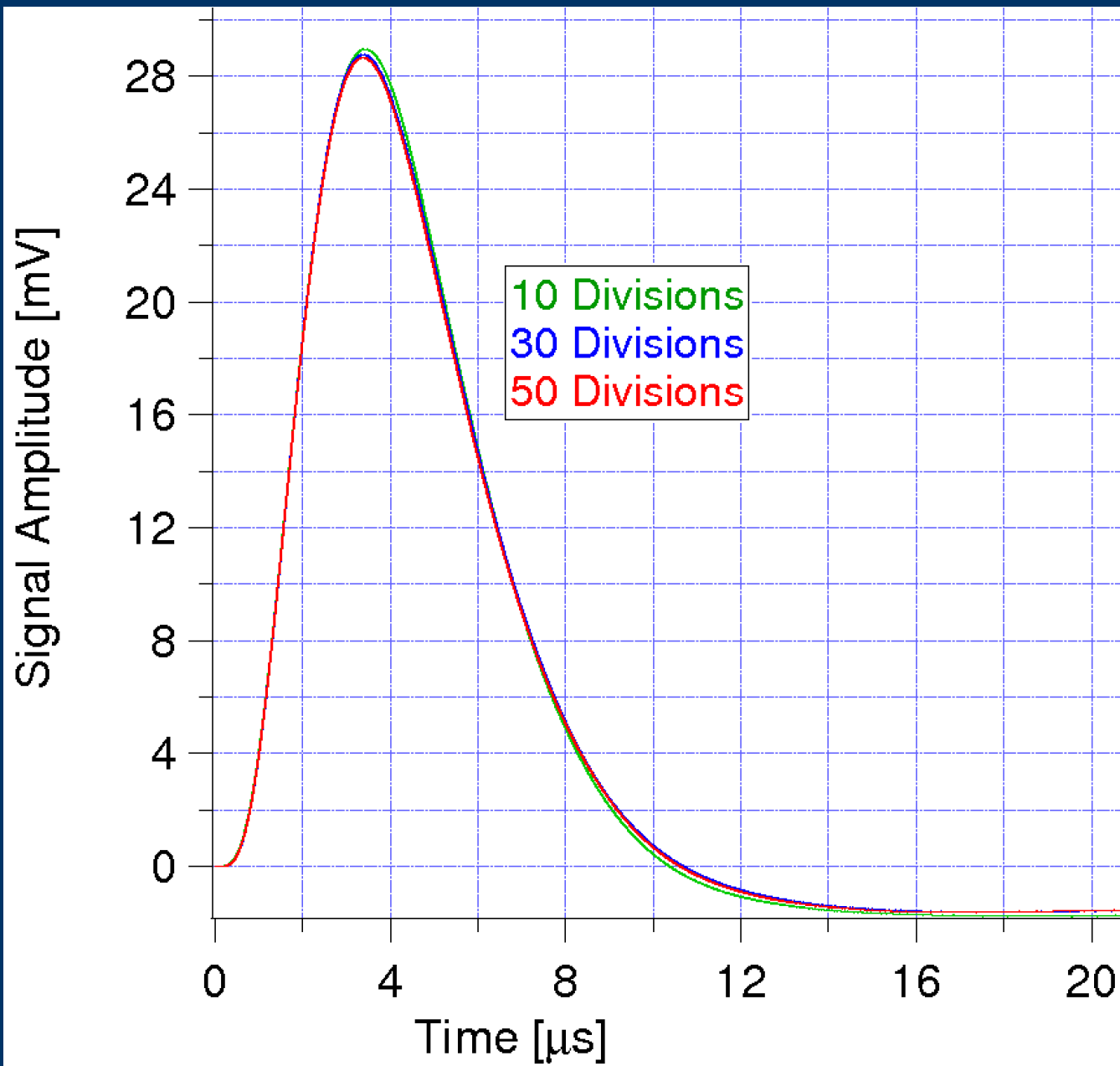


- Designed a pc board as a mock silicon strip detector with readout
- Use of a pc board was motivated by two factors.
 - Detectors designed specifically for charge division investigation were manufactured incorrectly making them unusable for this project
 - A pc board model is easier anyways!

10cm Detector Model:

- Total R = 600k Ω
- Total C = 12.5pF





- Pspice Simulation
- Used 600kΩ, 12.5pF divided equally between 10, 30, 50 divisions.
- Used same shaping function for all three cases.
- Result shows that the 10 division model has sufficient granularity to approximate a continuous distribution.



PC Board Model Of A Five Channel Silicon Strip Detector With Charge Division Readout

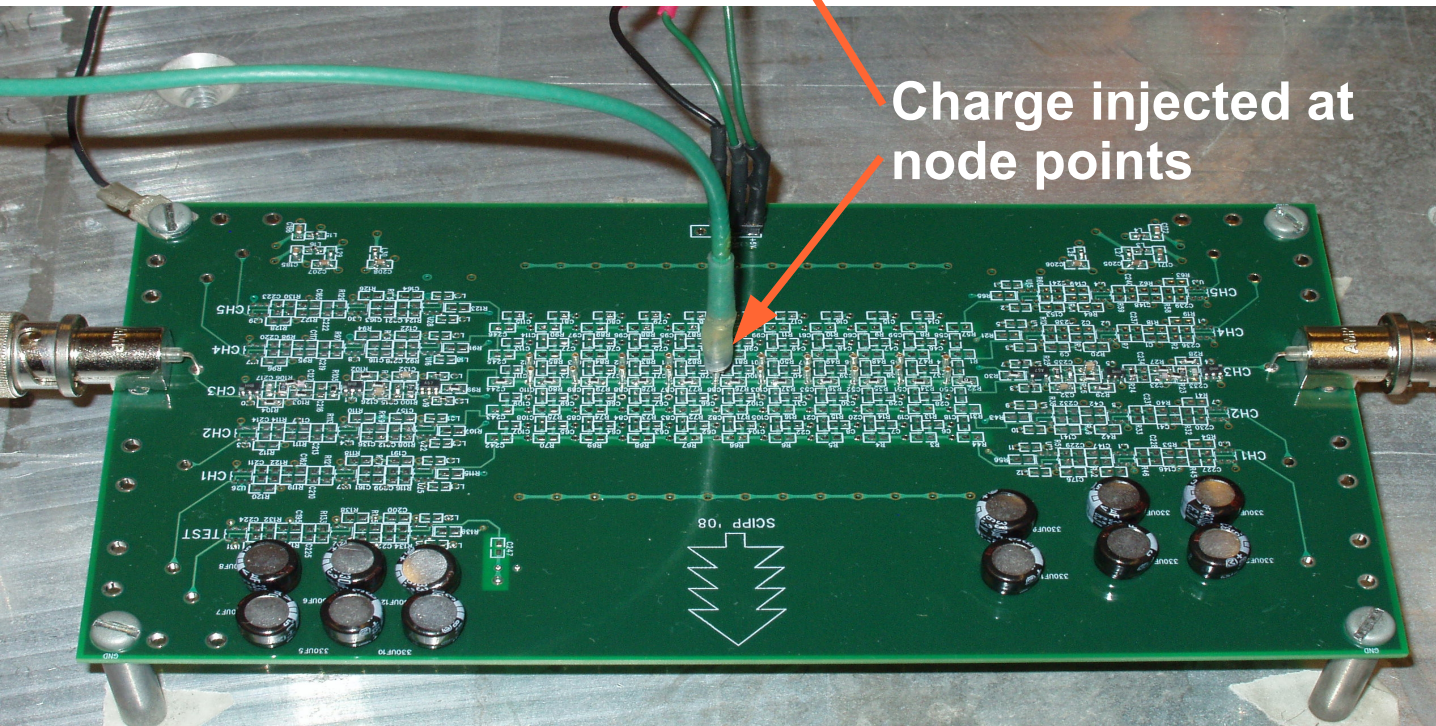
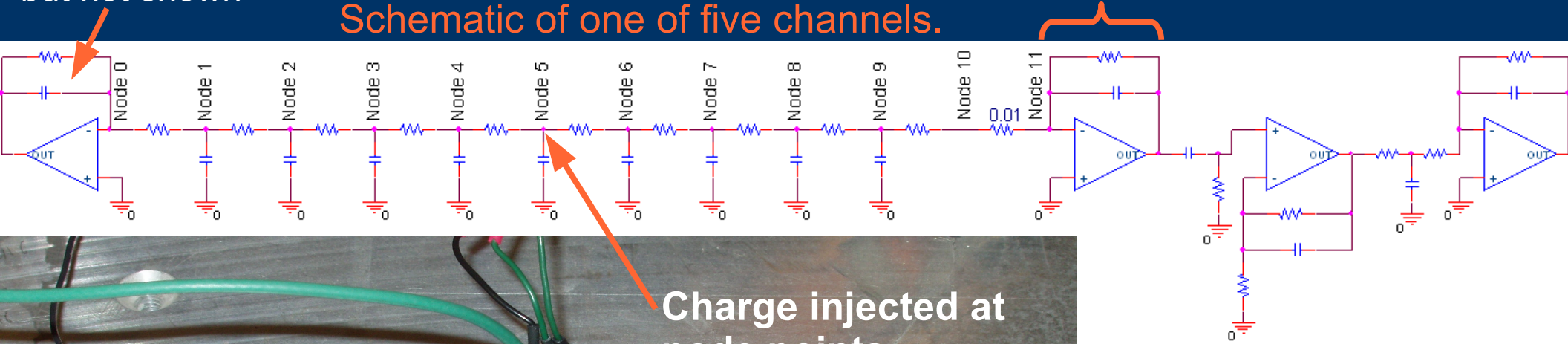


SCIPP

Left side amplifier design is identical to the right side, but not shown

Preamp is a high GBP charge sensitive integrator.

Schematic of one of five channels.



Charge injected at node points

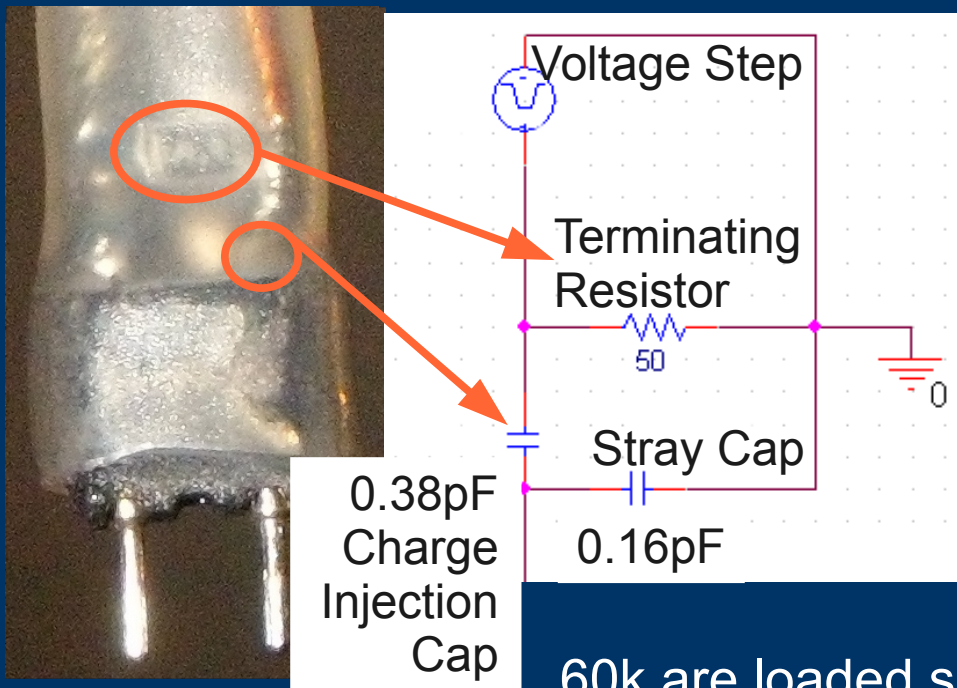
- Three stage integration, with the shaping time of each stage $\approx \frac{1}{3}$ total shaping time
- AC coupled to preamp via differentiation with long shaping time to minimize undershoot



Characterizing Stray Capacitances On The PC Board And Charge Injection Probe



SCIPP



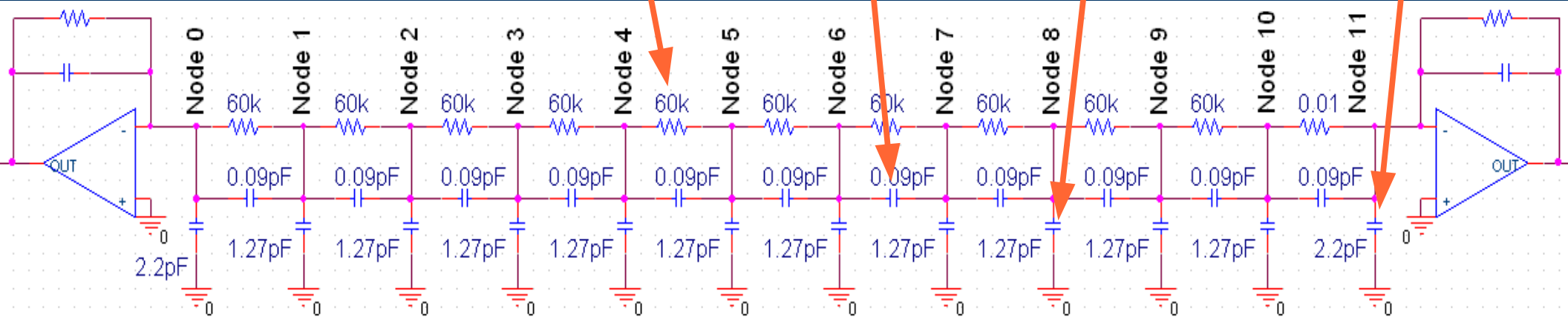
Used HP 2GHz LCR Meter With Kelvin Style Test Probe

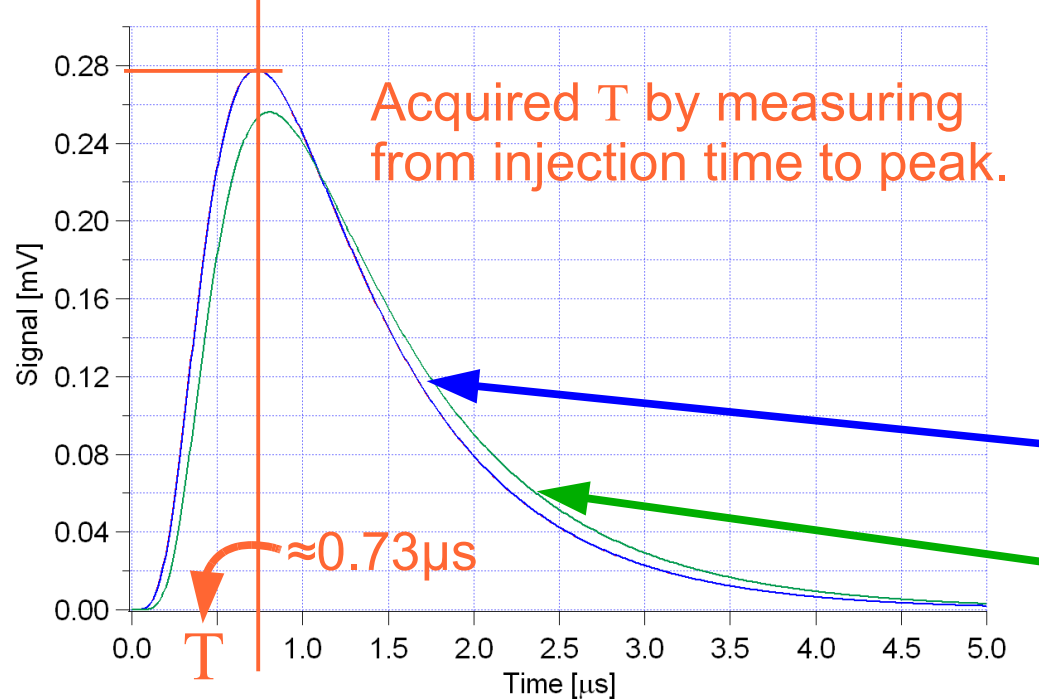
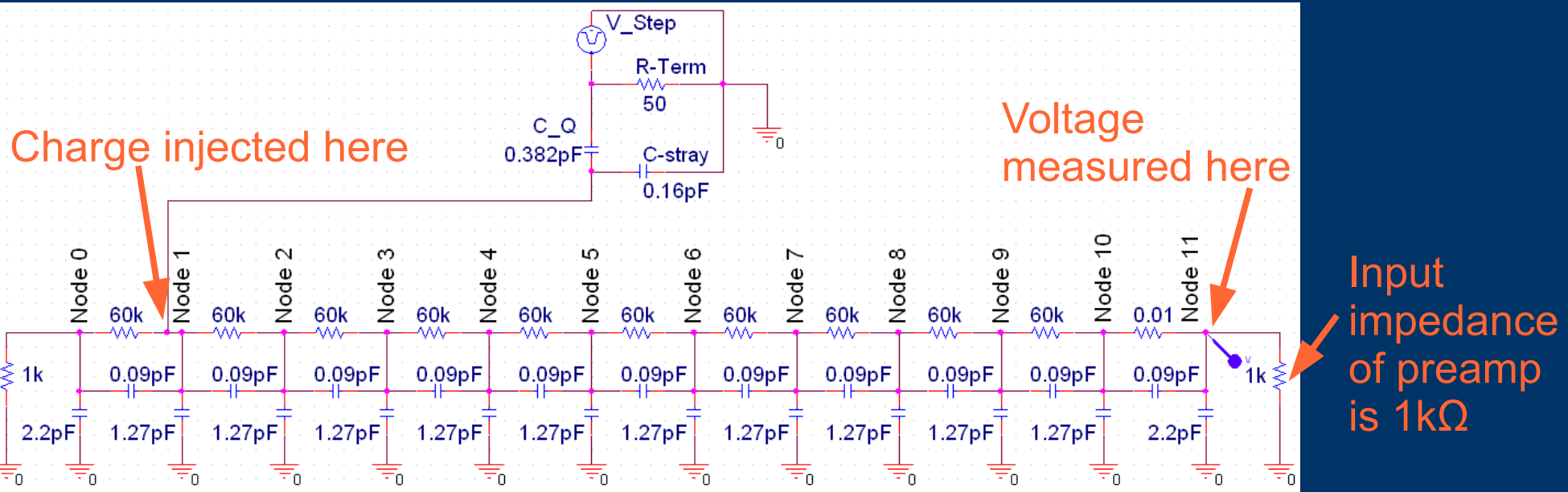
0.09pF shunt capacitance due to both surface mount pads and part.

2.2pF from trace on input of preamp.

60k are loaded surface mount resistors

1.27pF to ground plane is all parasitic from pads and traces. No loaded capacitance.

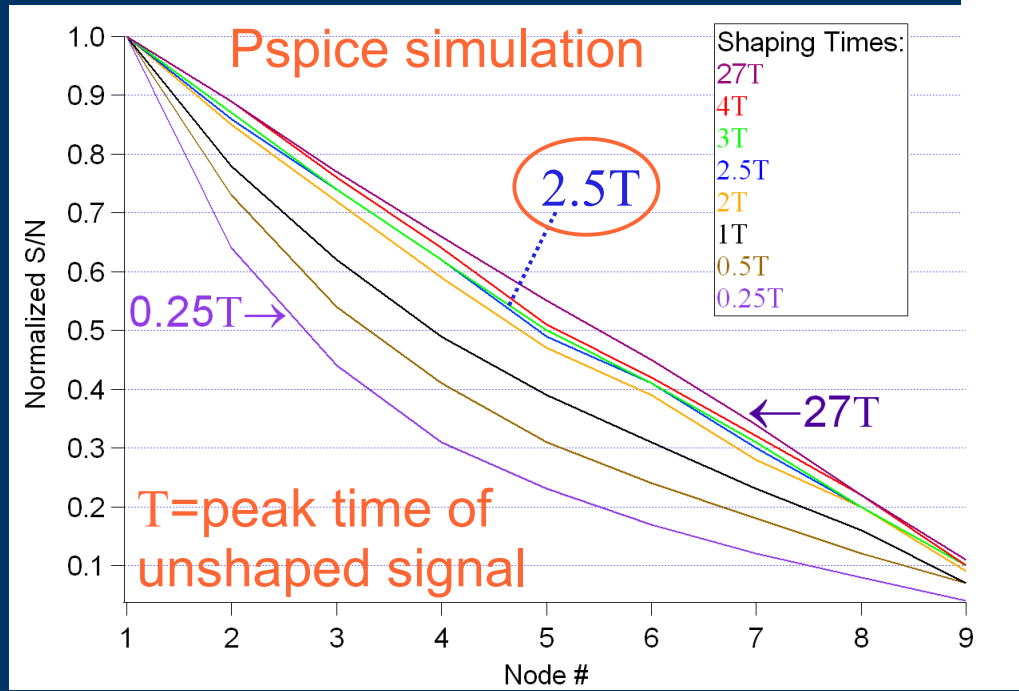
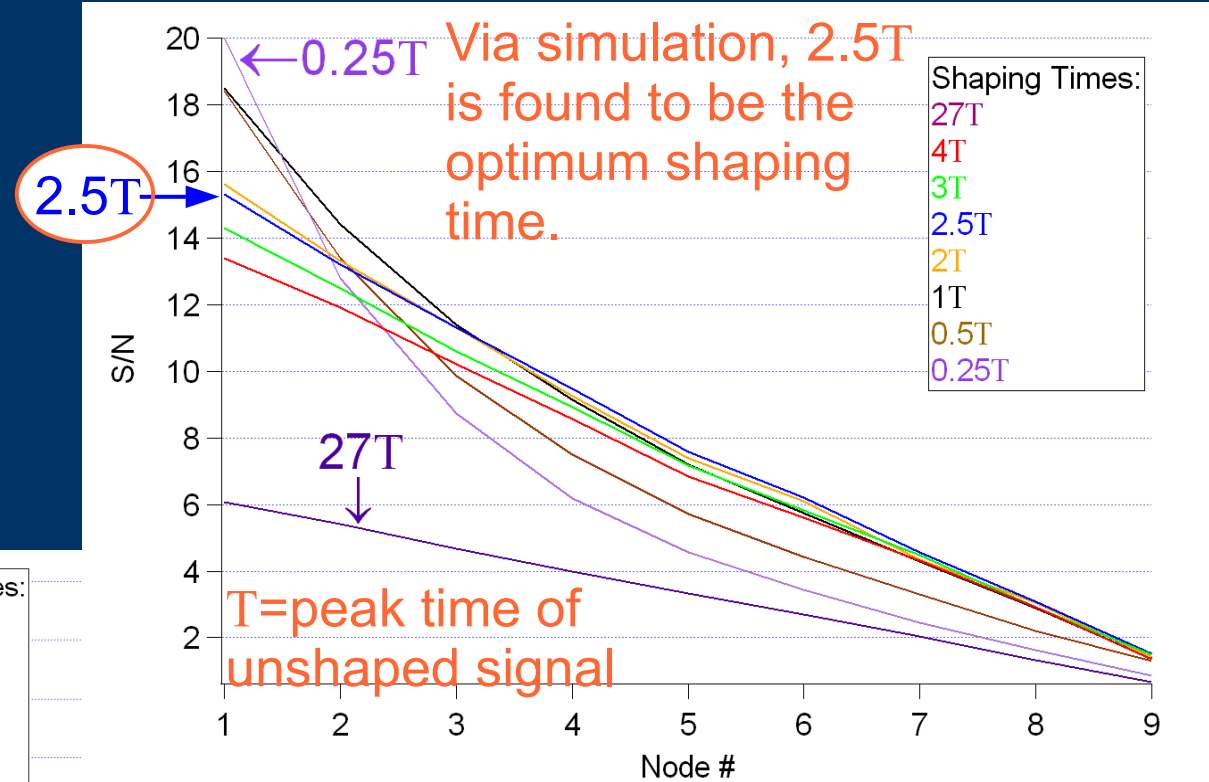




- I define T as the time constant from node 1 to node 11 (or node 9 to node 0).
- $T \approx (1/10)R_D C_D$
 - R_D = total strip resistance
 - C_D = total strip capacitance
- Blue signal is the 600k 12.7pF diffusive line shown above.
- Green signal is a 600k 12.7pF diffusive line with 0.09pF and 2.2pF strays removed.



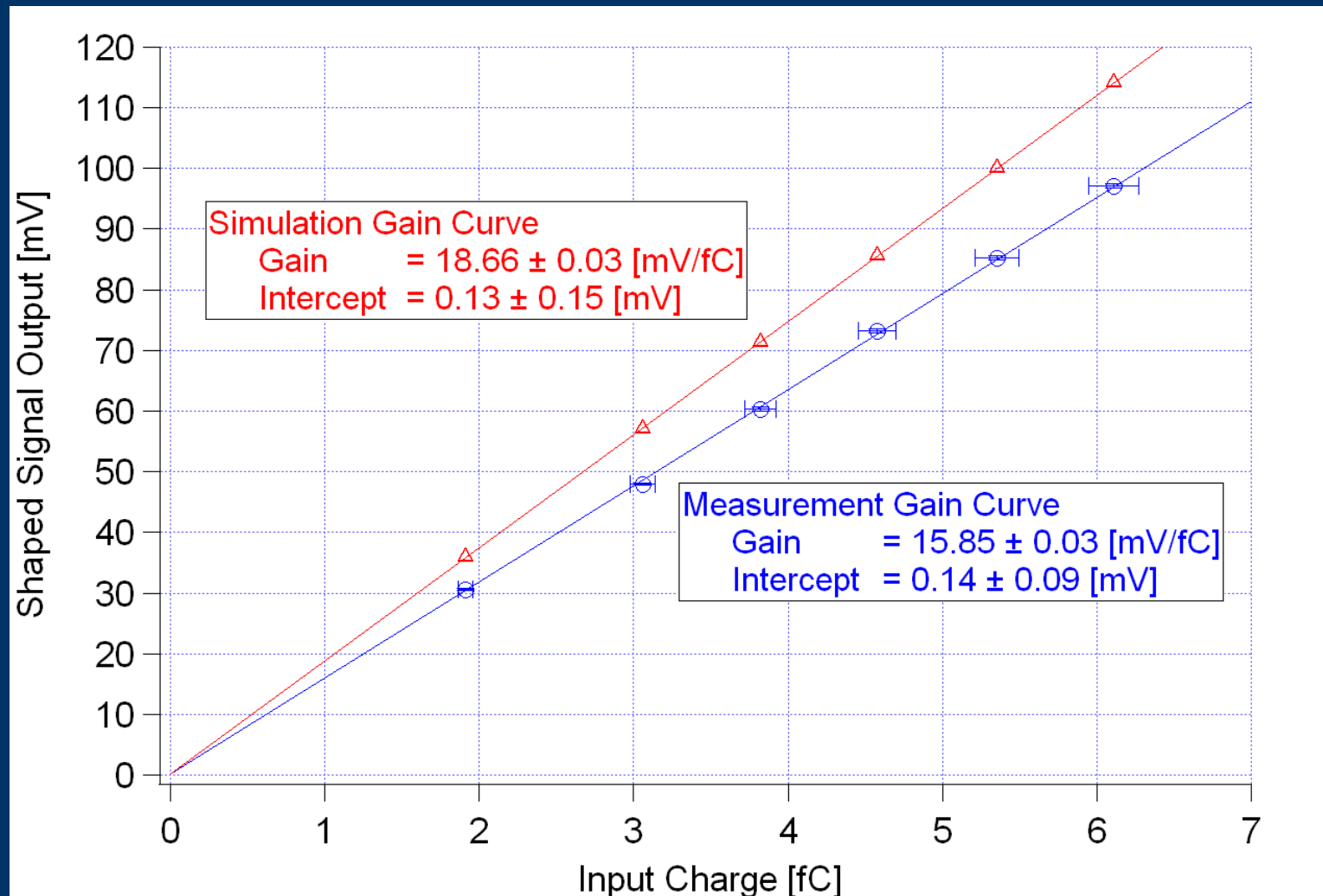
- Using the Pspice simulations shown here, we find that the optimum S/N occurs for a shaping time of $\tau \approx 2.5T \approx 0.23R_D C_D$
- shown as the **blue line**.



S/N vs. position

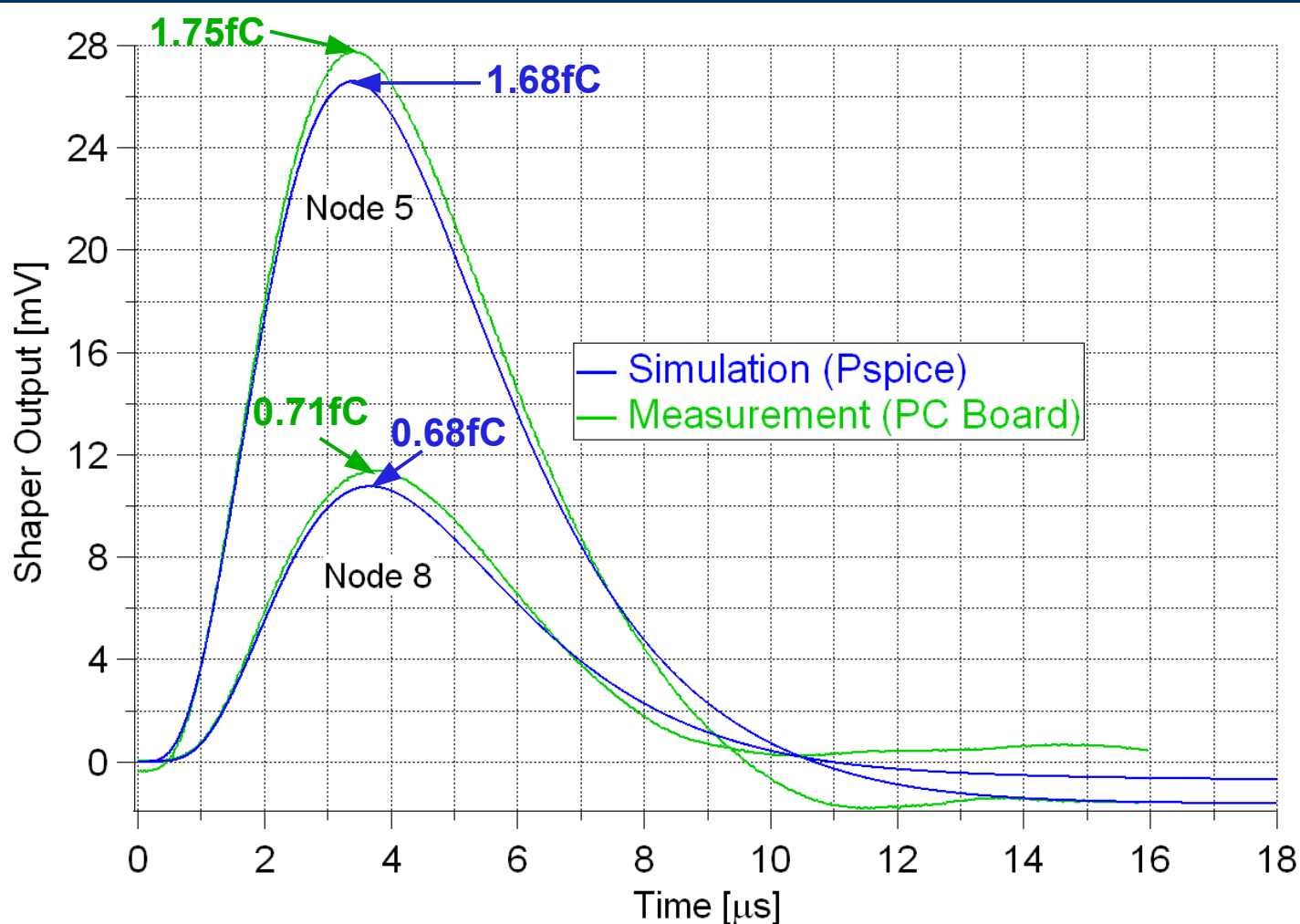
- Radeka estimates that the optimum S/N occurs for a shaping time of $\tau \approx 3T \approx 0.27R_D C_D$
- shown as the **green line**.

Normalized full scale S/N vs. position



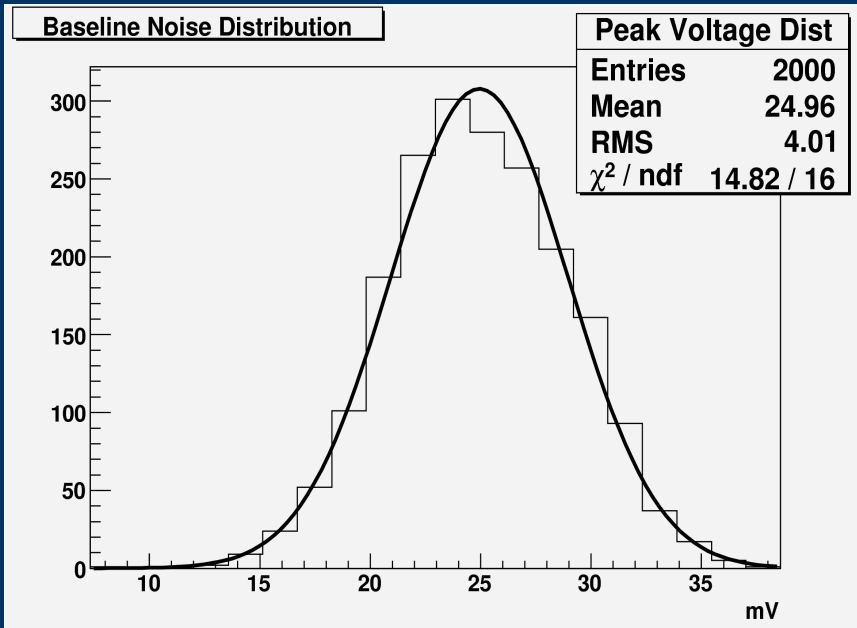
- First step is to determine the gain curves for the simulation and the pc board.
- PSpice gain tends to be larger because of ideal components.

Gain curves for simulation and pc board
for 600kΩ, 12.7pF detector model with 2.5T shaping time



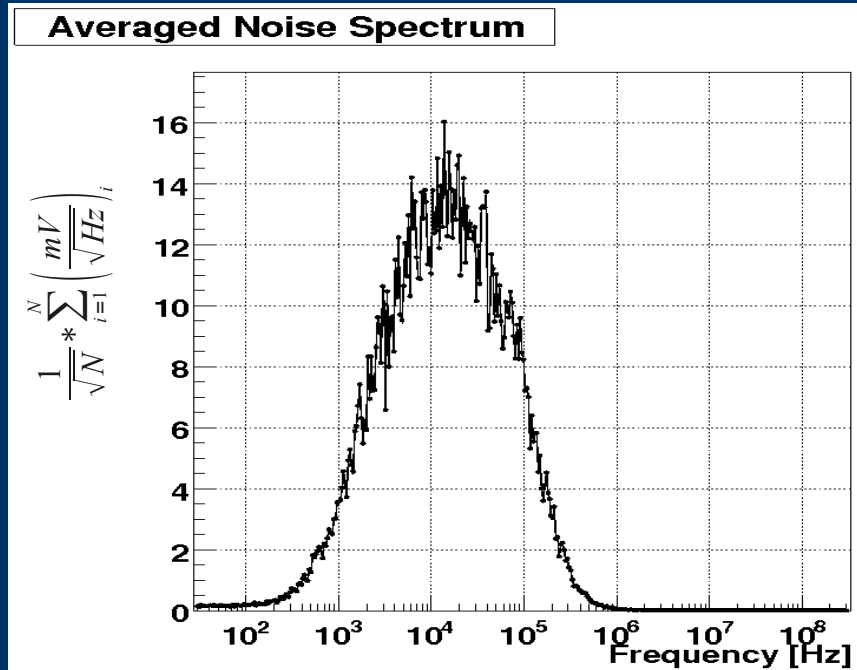
- Target rise time is 1.83μs (2.5T) from 1%→peak.
- Can see additional rise time added by diffusive line RC network which motivates the rise time method.
- Rise times differ by $\approx 5\%$.
- Peak charge values differ by $\approx 4\%$.
- e^{-1} fall times differ by $\approx 2.5\%$.

Comparison of shaper output between simulation and measurement for 600kΩ, 12.7pF, 2.5T shaping time.



R=600k Ω C=12.7pF

Measurement Method	Noise [mV]	Noise [fC]
Trace Merging	3.67	0.23
Spectrum Analyzer	3.80	0.24
Oscilloscope RMS	4.01	0.25

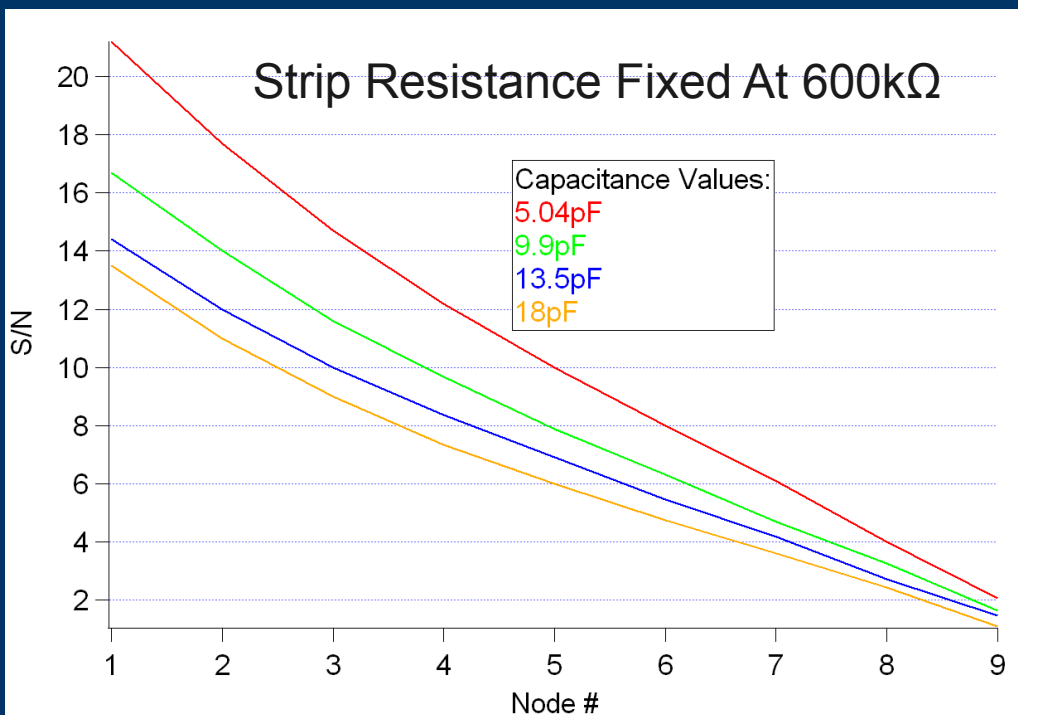
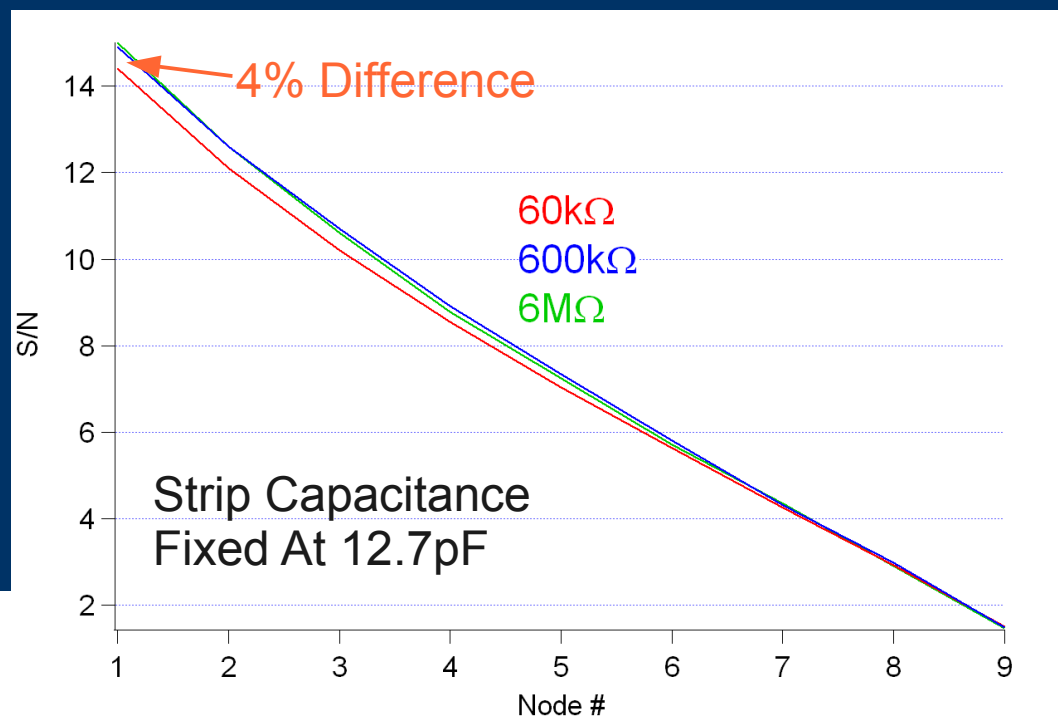


Pspice Prediction	3.69	0.23
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- Noise measurement agrees amazingly well with Pspice prediction!!
- We have confidence in the Pspice model.
- Pspice shows opamp noise contribution is less than 1% confirming that the noise is dominated by the RC network

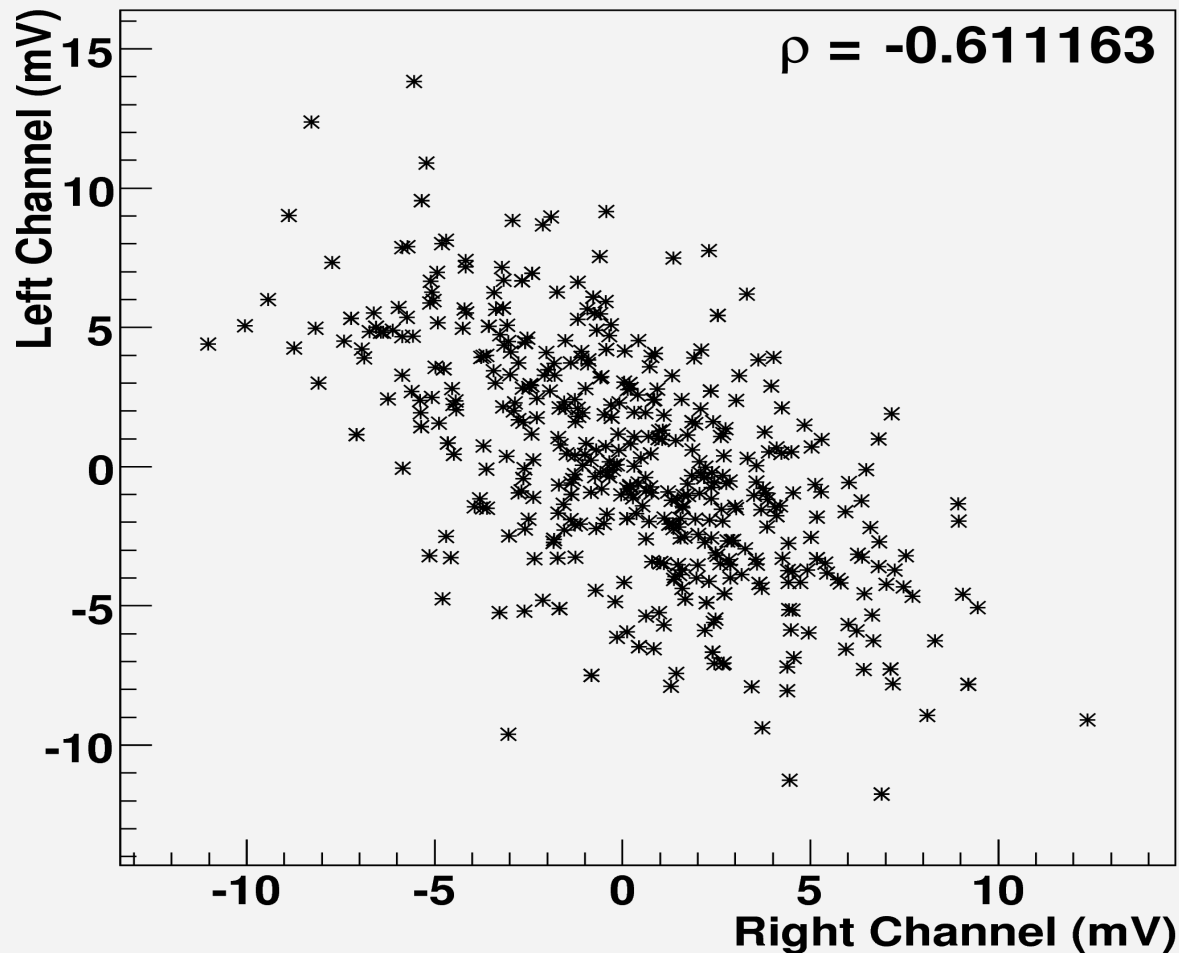
2.5T shaping time for all measurements

- Pspice simulation confirms the claim that S/N is independent of strip resistance.



- We do see a dependence on strip capacitance.
- Recall that Radeka predicted a \sqrt{C} dependence of the longitudinal resolution.

Noise Correlation Data



- Measured an anti-correlation in noise between the left and right sides of $\rho = -0.61$
- Anti-correlation is predicted qualitatively by Radeka for shaping times in the linear regime.



$$P = \frac{Q_R}{Q_L + Q_R} = \frac{\alpha}{1 + \alpha} = \text{fractional position}$$

$$\alpha = \frac{Q_R}{Q_L}$$

Anti-correlation factors in here

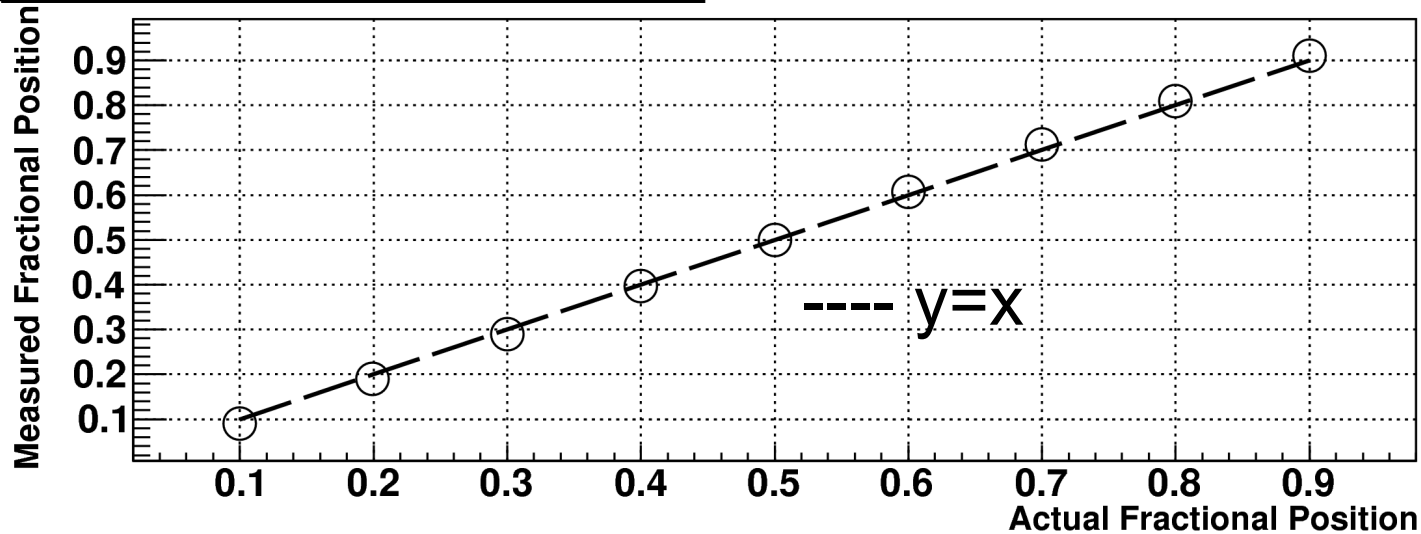
$$\sigma_\alpha = (\alpha) \left\{ \left(\frac{\sigma_R}{Q_R} \right)^2 + \left(\frac{\sigma_L}{Q_L} \right)^2 - 2\rho \left(\frac{\sigma_R}{Q_R} \right) \left(\frac{\sigma_L}{Q_L} \right) \right\}^{\frac{1}{2}}$$

$$\sigma_P = \left| \frac{dP}{d\alpha} \right| \sigma_\alpha = \left(\frac{1}{(1 + \alpha)^2} \right) \sigma_\alpha$$

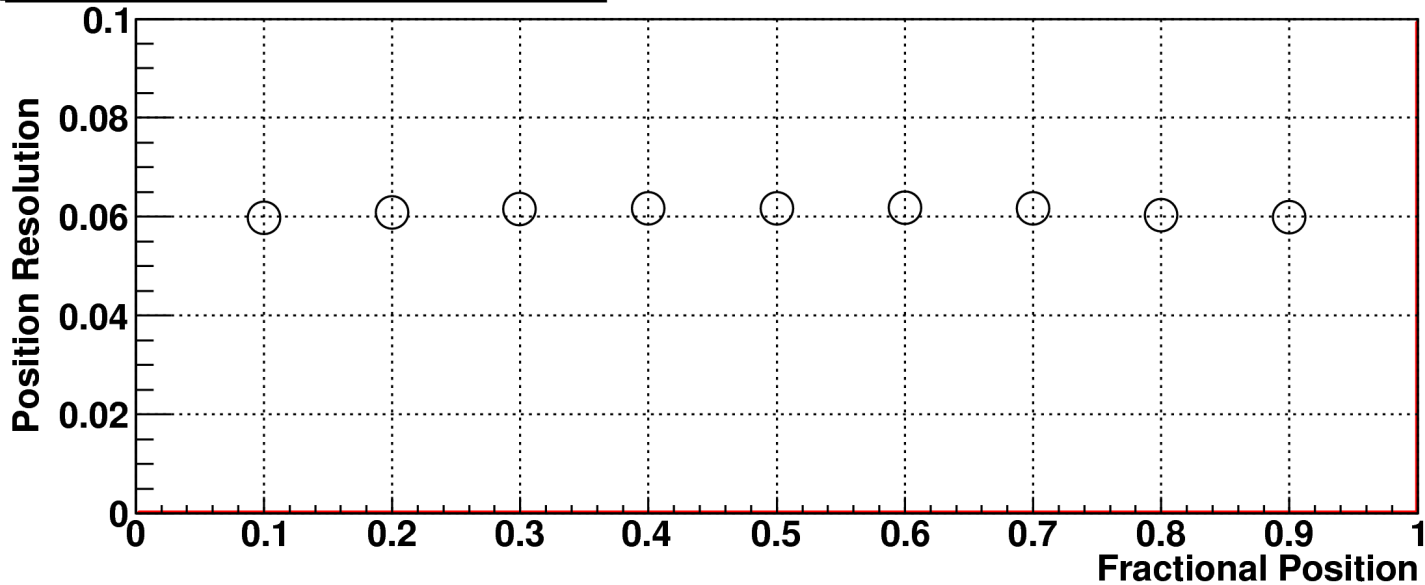
- We measure σ_p to be $\approx 6.1\text{mm}$ for a 10cm, 600k Ω , 12.7pF silicon strip detector
- Radeka predicts σ_p to be $\approx 6.5\text{mm}$ for a 10cm, 600k Ω , 12.7pF silicon strip detector.
- Asymmetry in σ_p due to slight non-linearity in 2.5T shaping time choice as well as measurement uncertainty.

	Node 1	Node 2	Node 3	Node 4	Node 5	Node 6	Node 7	Node 8	Node 9
Q_R [fC]	0.32	0.64	0.95	1.28	1.60	1.95	2.33	2.77	3.23
Q_L [fC]	3.24	2.75	2.33	1.94	1.60	1.26	0.94	0.65	0.32
P	0.090	0.189	0.290	0.400	0.500	0.607	0.713	0.810	0.910
$\sigma_R = \sigma_L$ [fC]	0.24	0.24	0.24	0.24	0.24	0.24	0.24	0.24	0.24
σ_p	0.0598	0.0609	0.0615	0.0616	0.0617	0.0618	0.0617	0.0603	0.0600

Calculated Position vs. Actual Position



Position Resolution vs. Position



- Measured position correlates very well with actual charge injection position.
- Longitudinal position resolution is independent of position

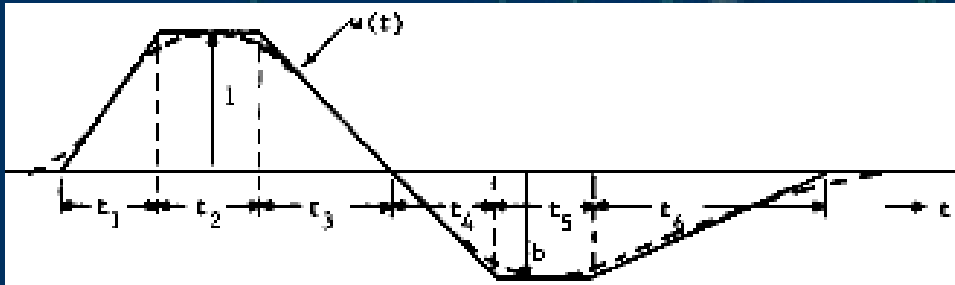
Implications of these results

- Predictions appear to be correct, even for very large resistances.
- Useful for pattern recognition without the use of a second layer.
- S/N results are the limiting factor in the accuracy of this charge division technique
- These results assume the information is read out in order to make these position measurements
- Because S/N is independent of strip resistance, improvement in resolution would come from a reduction in detector capacitance

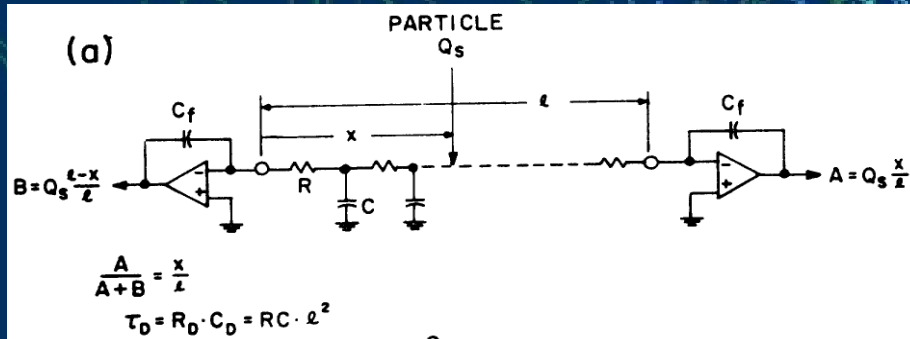
- Address capacitive coupling between channels of a silicon strip detector through the Pspice simulation developed here.
- Continue modification, by a fellow student, of a C++ pulse development simulation to do charge division in a silicon sensor
 - Investigate the impact by the charge division method on transverse resolution measurements
 - Explore the effect of signal sharing between neighboring strips on the longitudinal position resolution
- Think about viable methods that compensate for the low S/N
 - For example, communication between left and right side readout.

1. Radeka, V. "Signal, Noise, And Resolution In Position-Sensitive Detectors".
2. Alberi, J. L. and Radeka, V. "Position Sensing By Charge Division".
3. Kalbitzer, S. and Melzer, W. "On The Charge Dividing Mechanism In Position Sensitive Detectors".
4. A similar result for the propagation time is found by Kalbitzer and Melzer. They found a time equal to RC/π^2 .
5. Owen, R. B. and Awcock, M. L. "One And Two Dimensional Position Sensing Semiconductor Detectors".

Radeka's results and methods



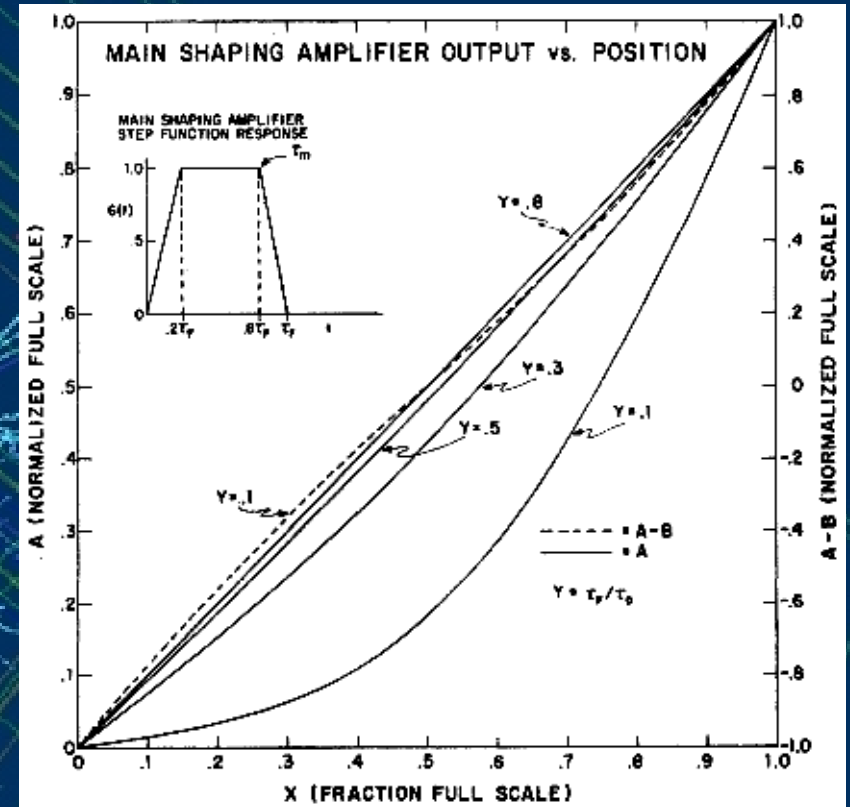
Trapezoidal fit method of signal analysis¹



Charge division schematic.¹

$$\sigma_P = 2.54 \left(\frac{\sqrt{kTC}}{Q_R + Q_L} \right) (FWHM)$$

Radeka's position resolution prediction.¹



Plot showing measured position for various shaping times²

Owen and Awcock results and methods

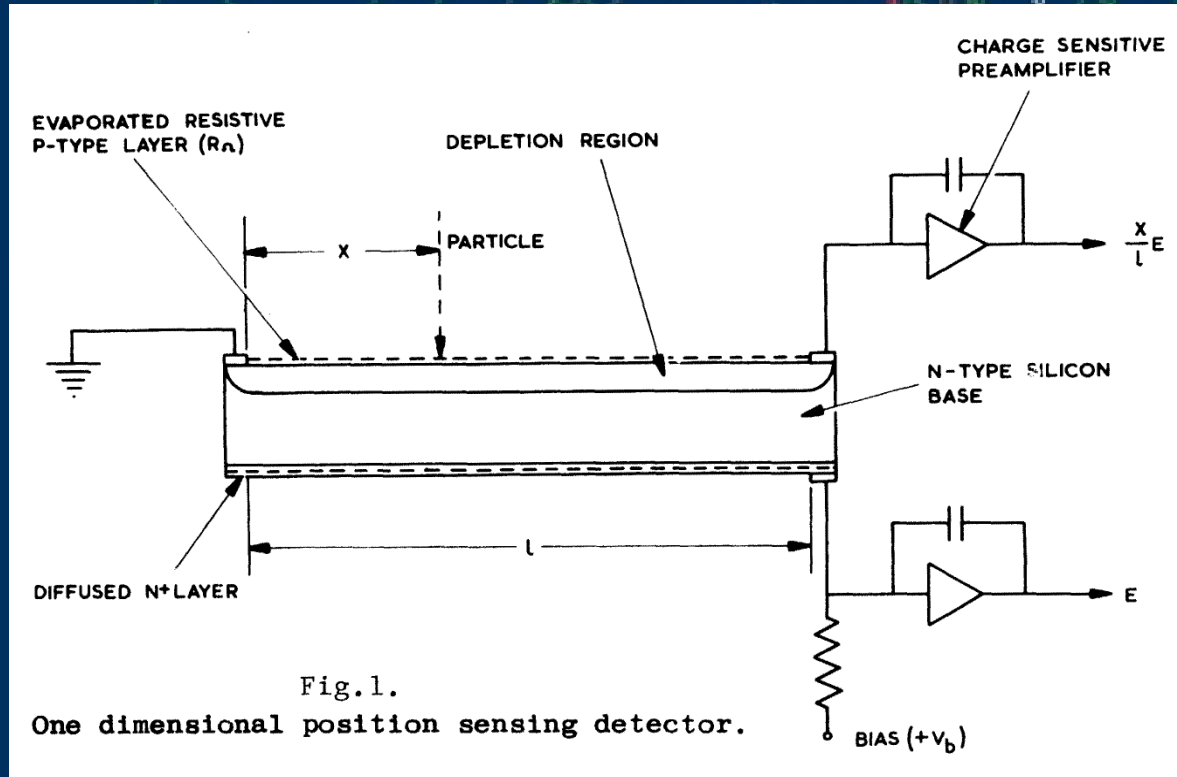


Table I

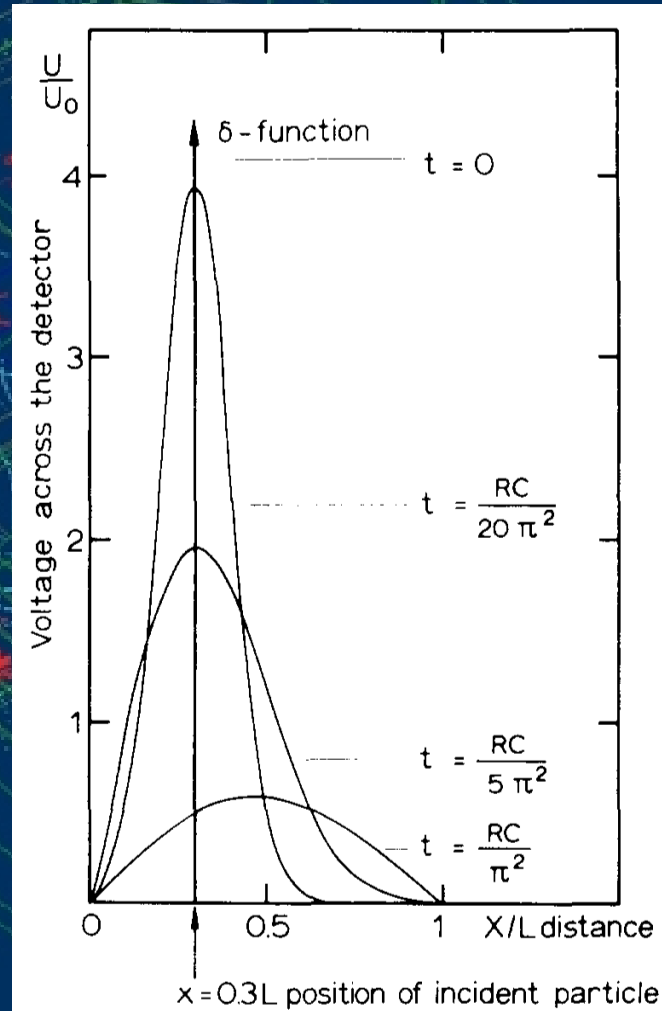
P/l	0	.1	.3	.5	.7	.9
τ_R	0	.28	.69	.84	.90	.90

From this it can be seen that there is little variation in rise time with position at the end distant from the amplifier.

This behavior is observed as well by the experiment presented here.⁵

Alternative charge division readout design.⁵

Kalbitzer and Melzer results and methods



Simulating
signal propagation time.³